L Number	Hits	Search Text	DB	Time stamp
1	42	wafer same roughness same backside near2 surface	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/26 10:56
3	1	wafer same rough$4 same backside near2 surface same (varied or various)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/26 10:56
4	1	wafer same rough$4 same backside near2 surface same radius	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/26 10:54
5	1	wafer same rough$4 same back adj side near2 surface same (radius or radially)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/26 10:55
8	25	wafer same roughness same back adj side near2 surface	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/26 10:56

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